

APPLICATION DATA SHEET

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Attorney Docket Number: BUR920000077

Publication Filing Type: new-utility

Application Type: utility

Title of Invention: SINGLE REACTOR, MULTI-PRESSURE CHEMICAL VAPOR
DEPOSITION FOR SEMICONDUCTOR DEVICES

Attorney Docket Number: BUR920000077

Legal Representative:

Attorney or Agent: Mr. Robert A. Walsh Esq.

Registration Number: 26516

Customer Number Correspondence Address: 000000



INVENTOR(s):

Primary Citizenship: U.S.A.

Given Name: Jack

Middle Name: O.

Family Name: Chu

Residence City: Manhasset Hill

Residence State: NY

Residence Country: US

Address: 44 Shelbourne Lane
Manhasset Hill NY, 11040

Primary Citizenship: India

Given Name: Basanth

Family Name: Jagannathan

Residence City: Beacon

Residence State: NY

Residence Country: US

Address: 966 Wolcott Avenue

[illegible]

Primary Citizenship:	U.S.A.
Given Name:	Ryan
Middle Name:	Wayne
Family Name:	Wuthrich
Residence City:	Burlington
Residence State:	VT
Residence Country:	US
Address:	161 Austin Drive, #67 Burlington VT, 05401